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Hi-Power and Large Area UV Exposure Systems - UV Flood Exposure Systems - UV Curing Systems - UV Photolithography - Mask Alignment Systems - UV Power Supplies - UV Power Meters - UV Mirrors

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LED LIGHTSOURCES

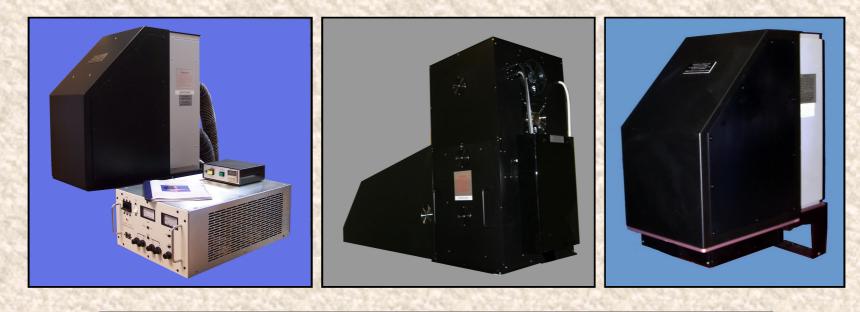
USED/DEMO SYSTEMS

LARGE AREA UV EXPOSURE SYSTEMS

B&A offers a variety of high performance, collimated UV Lightsources and UV Flood Exposure Systems. These systems are used for fine line patterning as well as the enhancement of many UV photolithography processes employed by the Microelectronics Industry. These UV systems are designed for production use as well as R&D applications. Near, Mid, and Deep UV systems are available with a variety of standard and optional features including beam sizes to 18" (450mm), intensity controlling powersupplies, and up to 5,000W capability.

The System's Optics...

The system's UV optics employ a proven, high performance optic train that include an elliptical reflector, dielectric heat removing primary and secondary mirrors, a multi-element optical integrator system and collimating optics. The system's optical integrator system produces uniformity and non-coherent radiation that virtually eliminates the detrimental effects of diffraction. These high intensity systems can resolve fine structures even in thick photosensitive materials.



Features and Options

- Uniform, Lightsource Systems
- Near, Mid and Deep UV Versions
- 200W to 5,000W Systems
- Intensity Controlling Powersupply Systems
- Shutter Controller
- Hi-Rel, Low Maintenance Design
- Excellent Documentation

Typical Applications

- Photoresist Patterning
- Photoresist Stabilization
- Edge Bead Exposure
- Photoresist Modification
- Image Reversal
- Polymer Research
- PCM Processes

Available Beam Sizes	100mm to 450mm	100mm to 200mm
Available beam Sizes	100mm to 450mm	100mm to 200mm
Beam Divergence	2.6 deg. to < 1.2 deg.	2.6 deg. to < 2.3 deg.
Beam Uniformity - Standard Systems	Diameters +/- 5% Squares +/- 6%	Diameters +/- 5% Squares +/- 6%
Beam - High Uniformity Systems	Diameters +/- 2.5% Squares +/- 3.5%	Diameters +/- 2.5% Squares +/- 3.5%
Beam Spectrum	340nm - 450nm	220nm - 260nm 240nm - 275nm
Intensity @ 1,000W (200mm Dia.)	30mW/cm ² (UV365) 60 mW/cm ² (UV400)	~8 mW/cm ² (DUV220) ~12 mW/cm ² (DUV260)
Intensity @ 2,000W (300mm Dia.)	27 mW/cm ² (UV365) 54 mW/cm ² (UV400)	~8 mW/cm ² (DUV220) ~12 mW/cm ² (DUV260)

TYPICAL TECHNICAL SPECIFICATIONS

3/24/2021

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http://www.bachur-n-associates.com/Large%20Area%20and%20Hi-Power%20UV%20Exposure%20Systems%20-%20Nov%202017.html